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DESCRIPTION JP2009030837A

10 Clean room air flow control system using image processing

[0001]

14 The present invention relates to a clean room air flow control system, and is particularly intended to realize energy saving and low cost operating cost. The present invention converts camera imaging in a clean room into image data using image processing, and differences in the image data. Regarding a clean room air flow control system that adjusts the air volume from.

[0002]

22 The semiconductor device-related manufacturing process is arranged in a clean room where the indoor air is maintained at a certain level of cleanliness. In general, clean rooms are classified according to the upper limit of cleanliness to be cleaned, equipped with equipment commensurate with each cleanliness, and designed and operated so as not to generate airborne dust exceeding each cleanliness. As a result, the standard for the operation of the clean room is set on the safer side, the operation is performed with an excessive amount of air blown, and the operation is performed by circulating a constant amount of air blown. The operation of the clean room is not controlled online and is independent of the fluctuation of airborne dust in the clean room, and a system with waste of energy and operating cost is realized.

[0003]

35 The conventional clean room conforms to the US federal standard 209B, and it seems that particulate matter in the air is controlled below the specified level, and environmental conditions such as temperature, humidity, and pressure are also controlled as necessary. It is